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(19) **United States**(12) **Patent Application Publication**
WAN et al.(10) **Pub. No.: US 2009/0146927 A1**(43) **Pub. Date: Jun. 11, 2009**(54) **METHOD FOR MANUFACTURING THIN FILM TRANSISTOR (TFT) AND OLED DISPLAY HAVING TFTS MANUFACTURED BY THE SAME**(30) **Foreign Application Priority Data**

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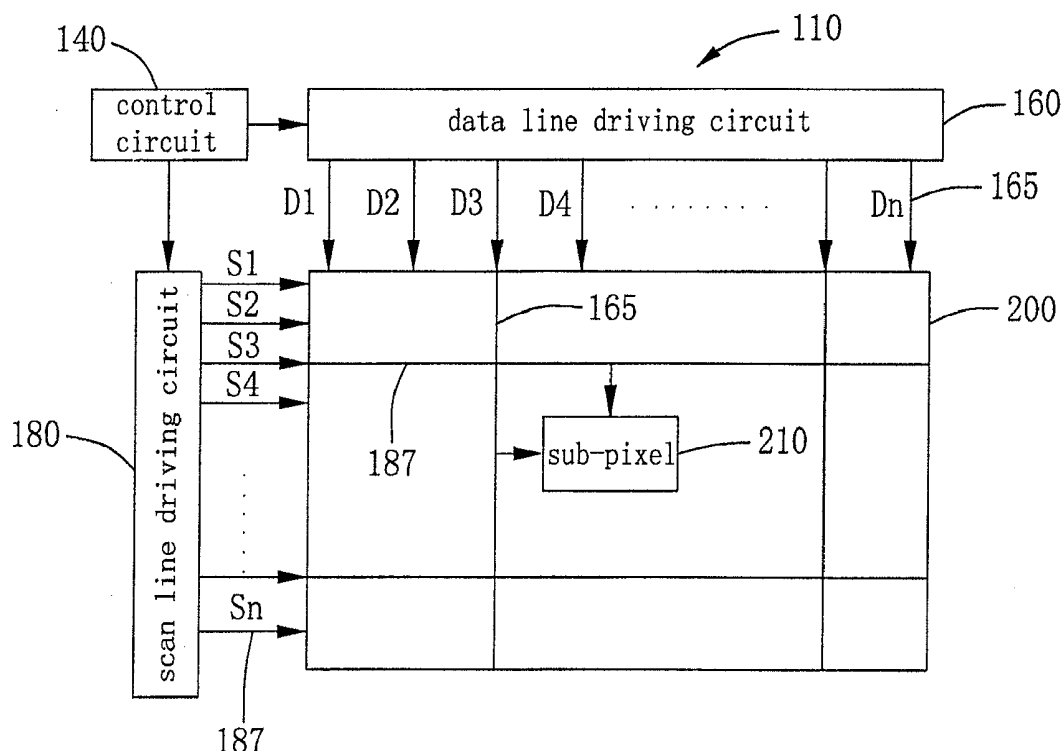
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H01L 21/84 (2006.01)(52) **U.S. Cl.** **345/76; 438/166; 257/E21.7**(57) **ABSTRACT**

An organic light emitting diode (OLED) display and thin film transistor (TFT) manufacturing method thereof are disclosed. According to the present invention, poly-silicon layers for forming active areas of non-driving TFT (e.g. peripheral circuit TFT and switch TFT) and driving TFT used in the OLED display are respectively made by using standard laser crystallization method and non-laser crystallization method or low energy laser crystallization method. Therefore, the peripheral circuit TFT has excellent electrical performance such as high carrier mobility, while the OLED-driving TFT has good stability so that the resultant display can operate with improved luminance uniformity.

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(60) Provisional application No. 61/012,042, filed on Dec. 6, 2007.



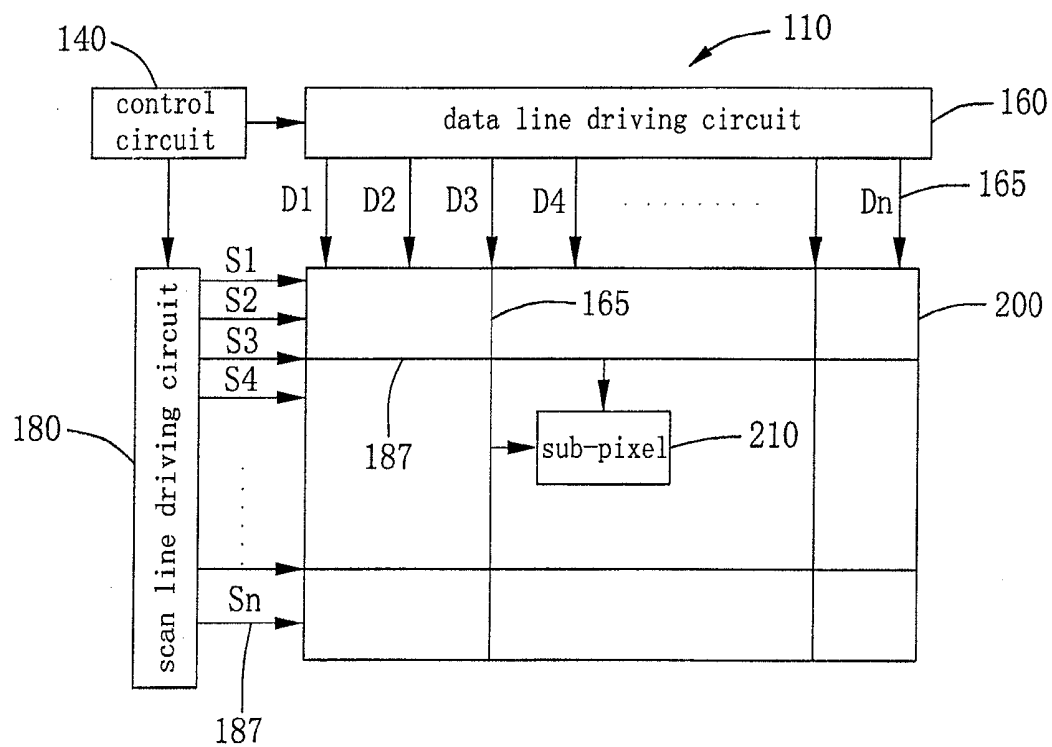


FIG. 1

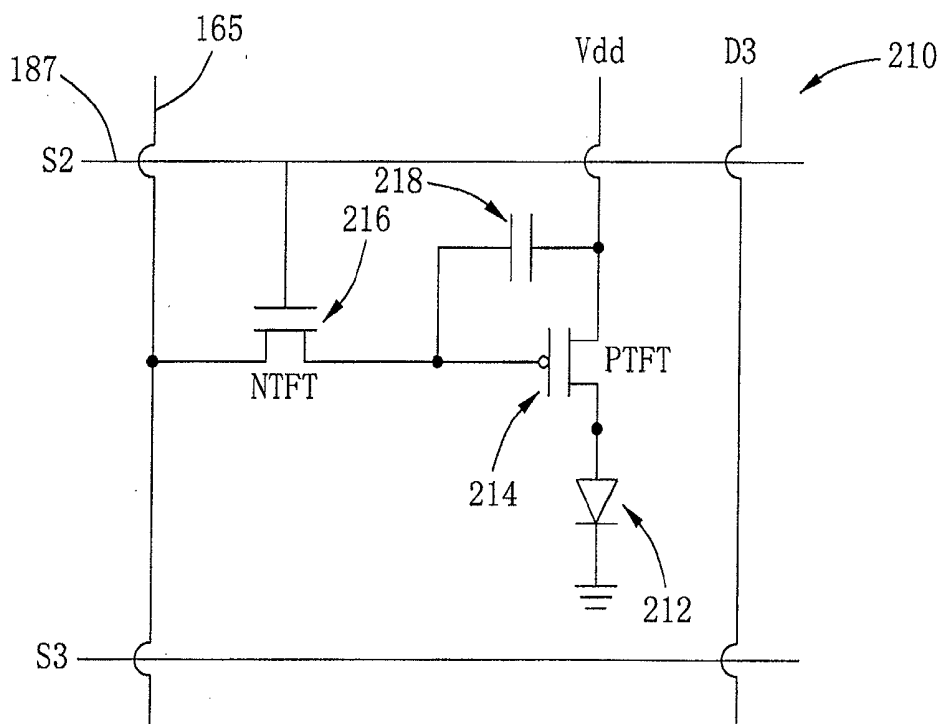


FIG. 2

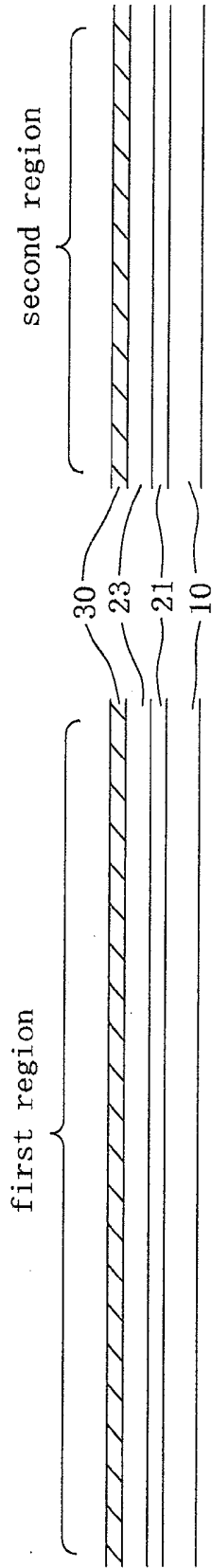


FIG. 3

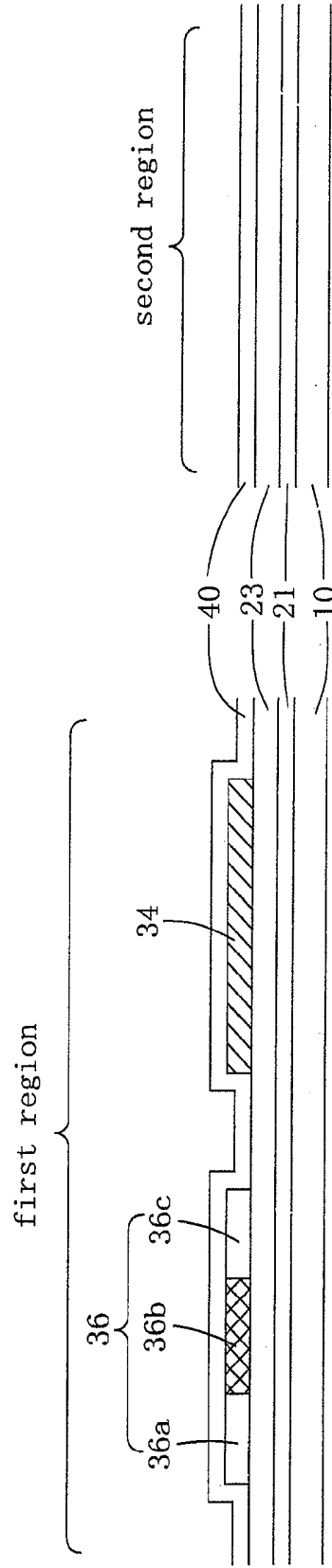


FIG. 4

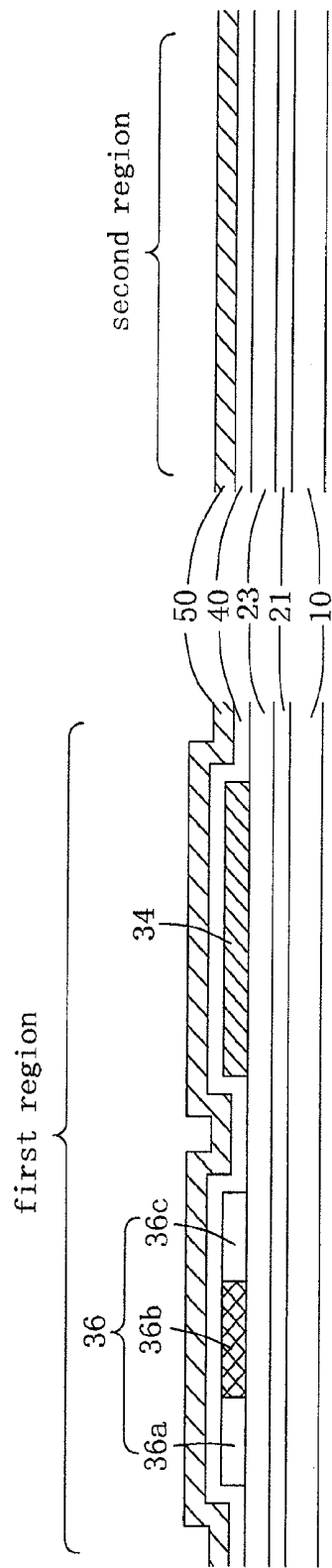


FIG. 5

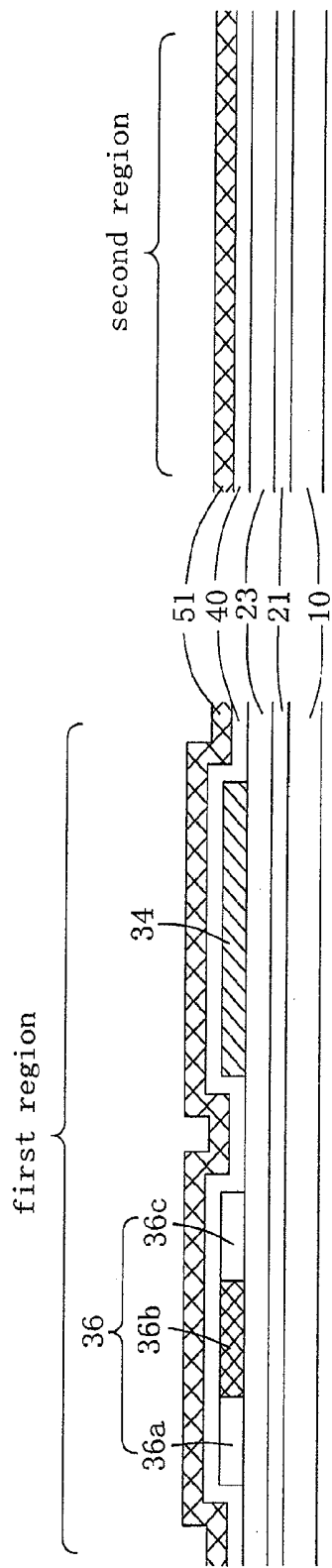


FIG. 6

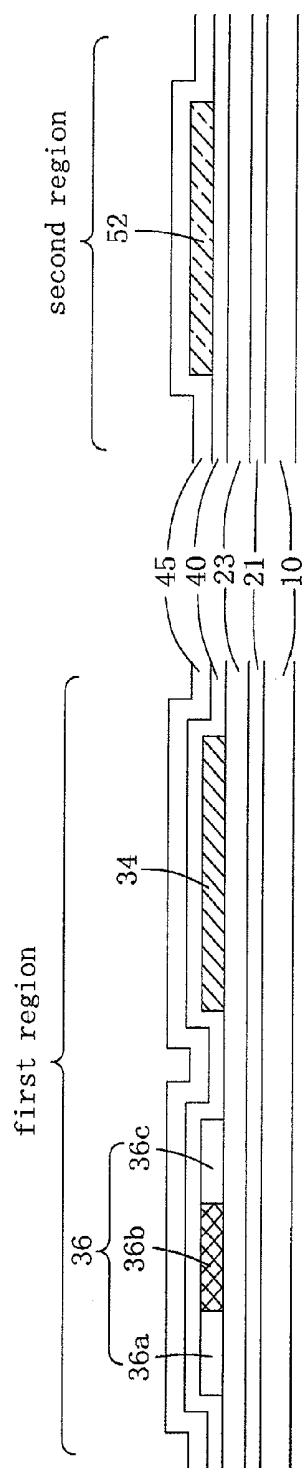


FIG. 7

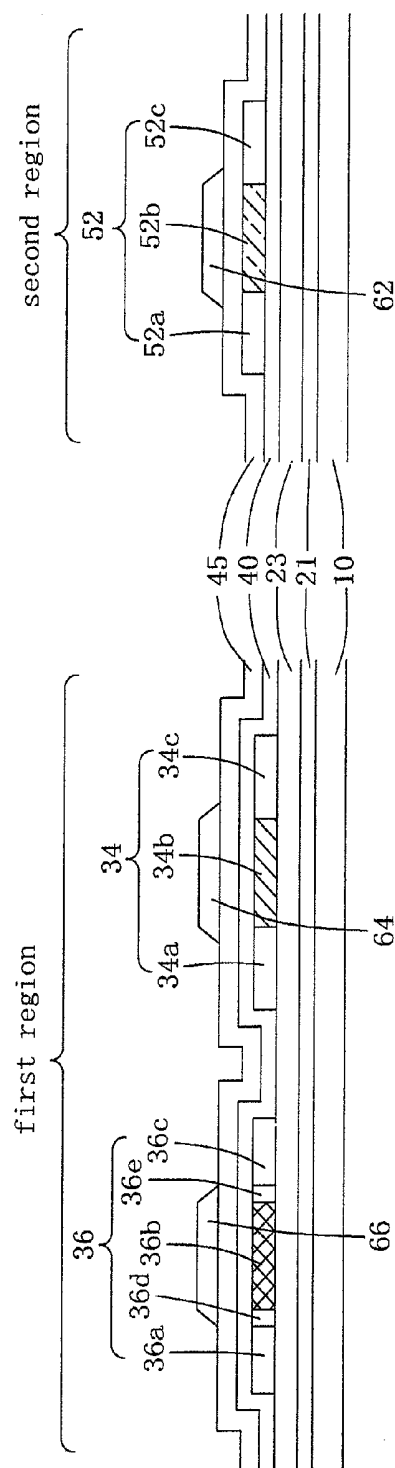


FIG. 8

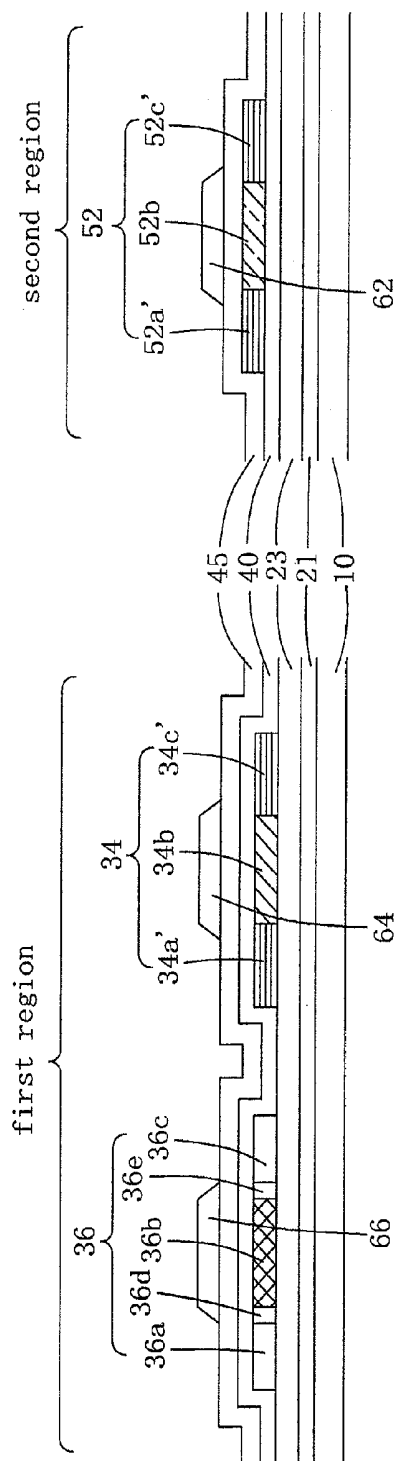


FIG. 9

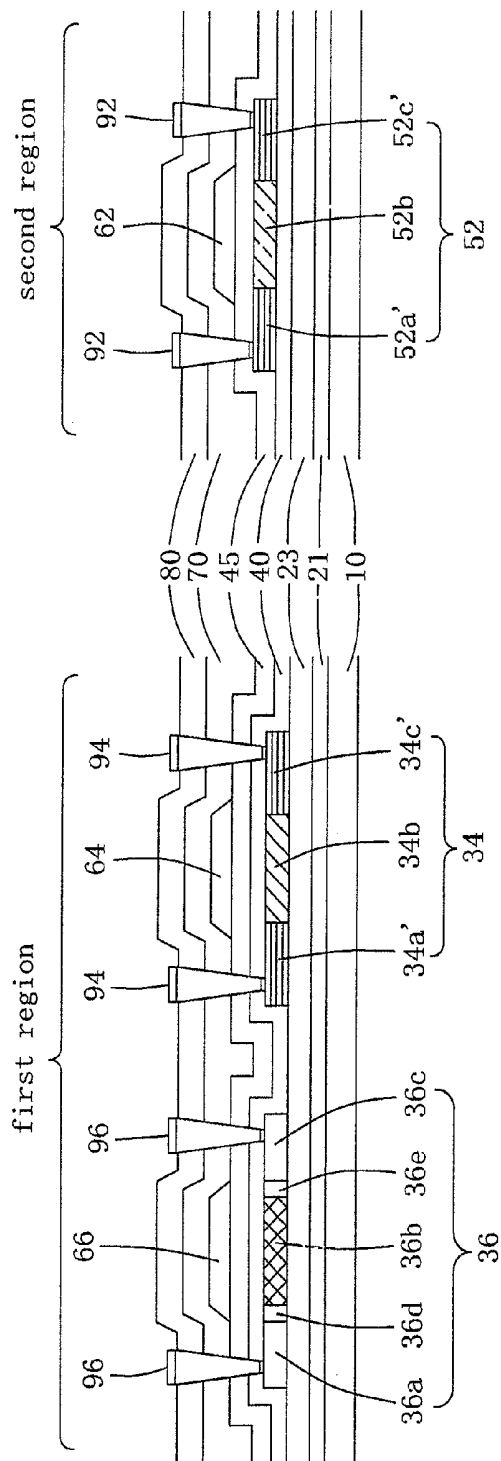


FIG. 10

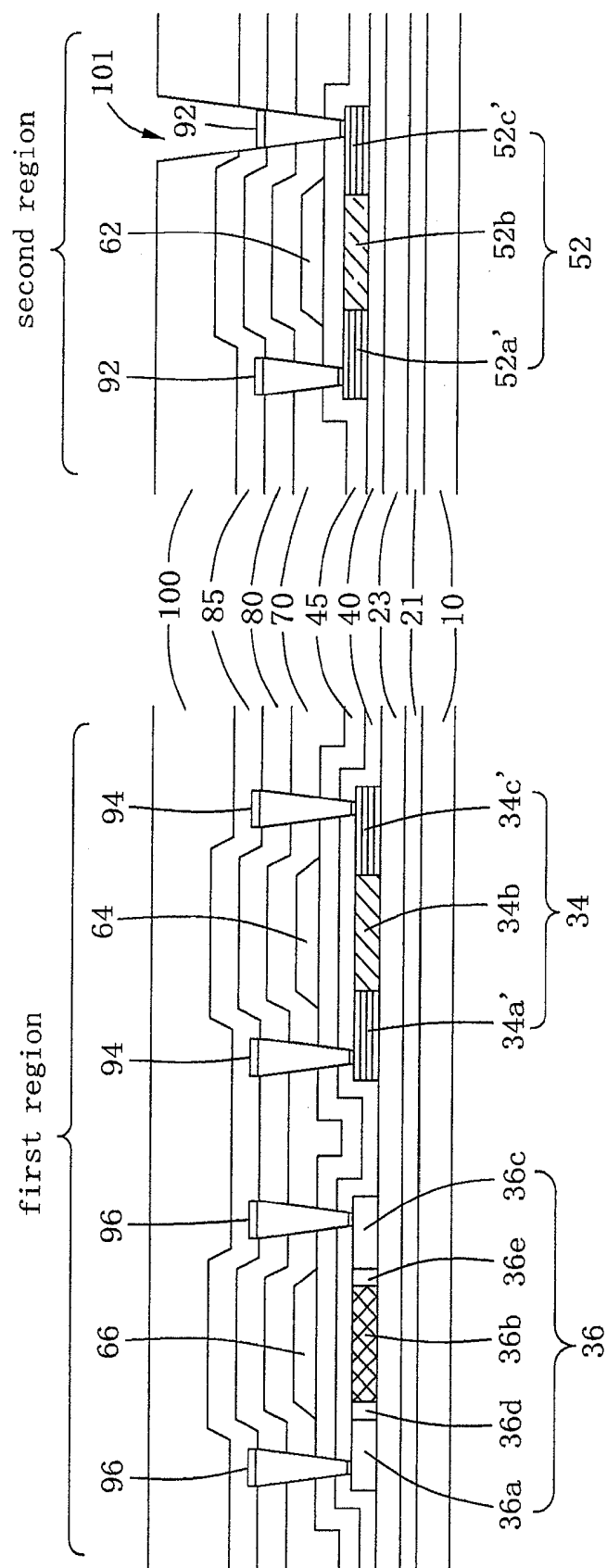


FIG. 11

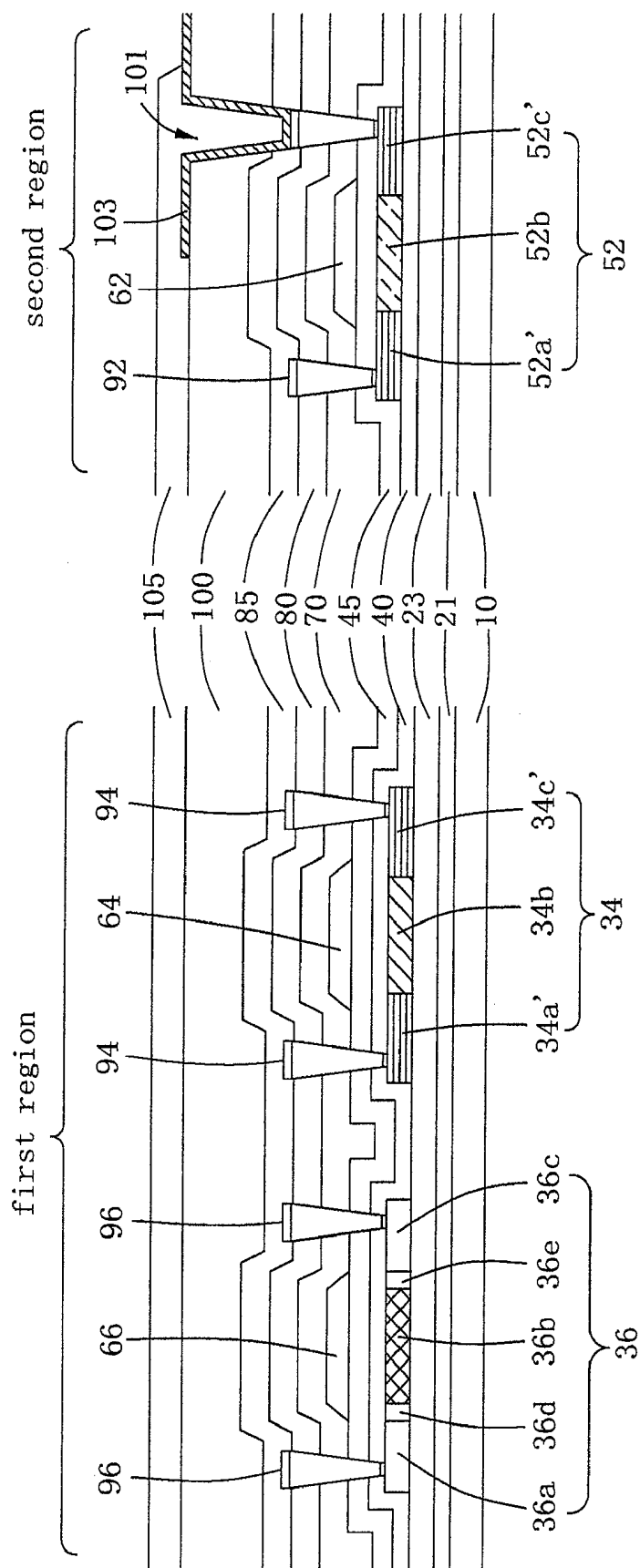


FIG. 12



FIG. 13

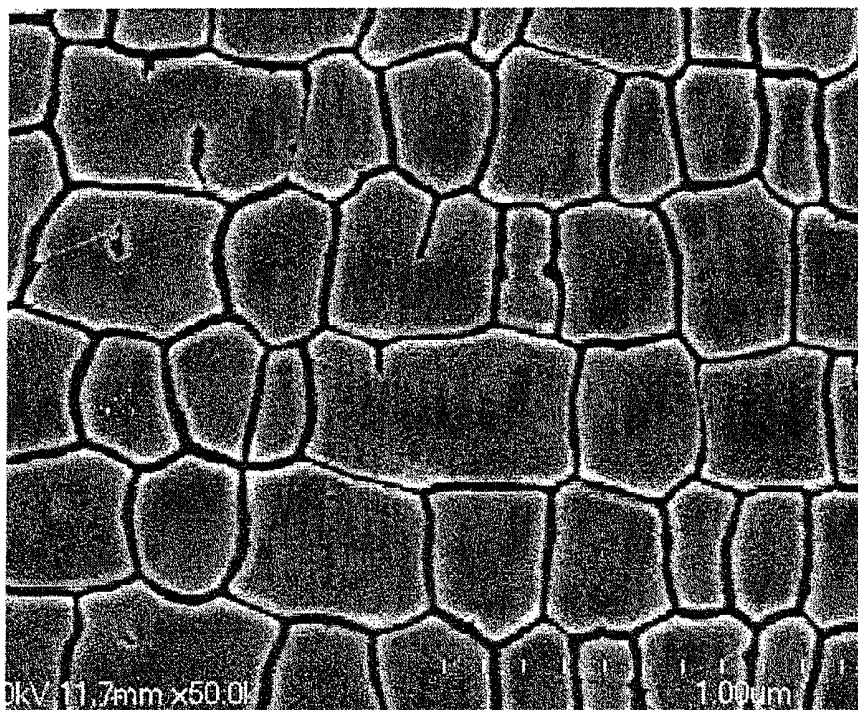
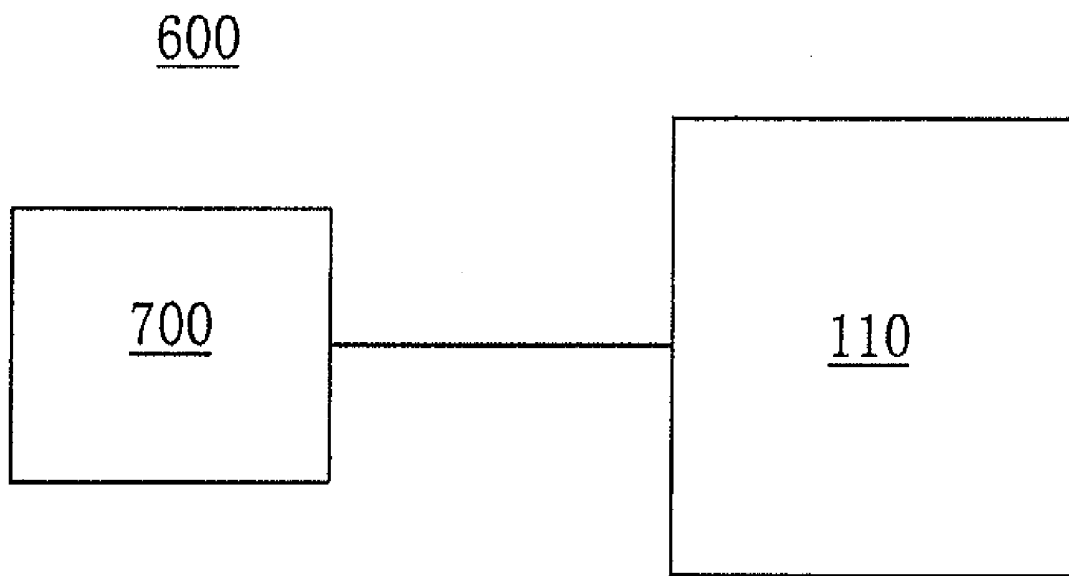


FIG. 14

**FIG. 15**

**METHOD FOR MANUFACTURING THIN
FILM TRANSISTOR (TFT) AND OLED
DISPLAY HAVING TFTS MANUFACTURED
BY THE SAME**

TECHNICAL FIELD OF THE INVENTION

[0001] The present invention relates to an active matrix organic light emitting diode (AMOLED) display, more particularly, to a method for manufacturing various thin film transistors (TFTs) used in AMOLED displays and an AMOLED display having such TFTs.

BACKGROUND OF THE INVENTION

[0002] Organic light emitting diodes (OLEDs) have been widely utilized in displays. An AMOLED display uses a driving circuit to drive a light emitting element, i.e. an OLED. The AMOLED driving circuit uses TFTs, including a switch TFT and a driving TFT. The switch TFT, which is implemented by an N-type TFT (NTFT), is used for switching the ON/OFF state of a sub-pixel of the display. The driving TFT, which is implemented by a P-type TFT (PTFT), is used for driving the light emitting element (e.g. an OLED). In addition, a peripheral circuit of the AMOLED display also needs to use NTFT and PTFT. Conventionally, polycrystalline silicon (also referred to as poly-silicon) used in the TFTs of the AMOLED driving circuit and peripheral circuit is made by using a standard laser crystallization method to lead amorphous silicon growing on a glass substrate to crystallize into poly-silicon. Not like a silicon wafer used for manufacturing general transistors, the glass substrate suitable for a flat display cannot endure high temperatures, and therefore it is required to use a crystallization technique in which the temperature is lower than the melting temperature of glass substrate. Accordingly, the standard laser crystallization method is used. However, the standard laser crystallization technique has a problem. During triggering crystallization, output laser energy errors will result in a luminance non-uniform phenomenon called "mura" in the resultant display.

[0003] Further, the AMOLED driving TFT drives the OLED by an output current. The light emitting result is very sensitive to the variation in the driving current. A display area has a driving TFT matrix for a plurality of sub-pixels. If there are differences among the electrical properties of the respective driving TFTs, then light intensities of OLEDs in this area will have corresponding differences, resulting in visible distinction for human's vision.

[0004] After being made into a display, standard laser technique, current driving and the like factors regarding the driving TFT may result in stripe mura, thereby causing the yield of AMOLED products to be low. The present invention is to solve such a problem.

SUMMARY OF THE INVENTION

[0005] An objective of the present invention is to provide an OLED display TFT manufacturing method for manufacturing N-type and P-type peripheral circuit TFTs for an OLED display peripheral circuit as well as a switch TFT and driving TFT used in a driving circuit of a display area. By using the method of the present invention, the manufactured peripheral TFT, switch TFT and driving TFT are respectively provided with different properties to meet the use requirements thereof. The peripheral circuit TFT and switch TFT have excellent electrical performance such as high carrier mobility. The

driving TFT has good stability so that the resultant display can operate with good luminance uniformity.

[0006] Another objective of the present invention is to provide an OLED display, which comprises a peripheral circuit portion and a display area portion. The peripheral circuit portion uses peripheral circuit TFTs. The display area portion has a plurality of sub-pixels, each sub-pixel contains a light emitting element, a driving TFT for driving the light emitting element and a switch TFT for switching a state of the sub-pixel. The peripheral circuit TFTs, switch TFT and driving TFT are respectively provided with properties meeting the use requirements thereof. The peripheral circuit TFT and switch TFT have excellent electrical performance such as high carrier mobility. The driving TFT has good stability so that the resultant display can operate with good luminance uniformity.

[0007] In accordance with an aspect of the present invention, an OLED display TFT manufacturing method comprises steps of providing a substrate, the substrate having a first region and a second region; forming a buffer layer on the substrate; forming a first poly-silicon layer on the buffer layer by a first crystallization process; patterning the first poly-silicon layer to form active areas of first TFTs; forming a first insulating layer; forming a second poly-silicon layer on the first insulating layer by a second crystallization process different from the first second crystallization process; patterning the second poly-silicon layer to form an active area of a second TFT; forming a second insulating layer; and respectively forming gates of the first TFTs and second TFT on the second insulating layer.

[0008] In accordance with another aspect of the present invention, an OLED display includes a peripheral circuit portion and a display area portion. The display area portion has a plurality of sub-pixels. Each sub-pixel has a light emitting element, a driving TFT for driving the light emitting element and a switch TFT. The OLED display comprises a substrate, first TFTs formed on the substrate. Each first TFT has a first buffer layer formed on the substrate, an active area made by a first poly-silicon layer provided on the buffer layer, a first gate insulation layer covering the active area and a first gate provided on the first gate insulation layer. The OLED display further comprises a second TFT formed on the substrate. The second TFT has a second buffer layer formed on the substrate, an active area made by a second poly-silicon layer provided on the buffer layer, a second gate insulation layer covering the active area and a second gate provided on the second gate insulation layer. The first poly-silicon layer and the second poly-silicon layer have different grain properties. In addition, the first gate insulation layer and the second gate insulation layer have different thicknesses.

BRIEF DESCRIPTION OF THE DRAWINGS

[0009] The present invention will be described in detail in conjunction with the appending drawings, in which:

[0010] FIG. 1 is a schematic diagram showing a basic circuit structure of an AMOLED display;

[0011] FIG. 2 schematically shows a basic circuit structure of a sub-pixel;

[0012] FIG. 3 to FIG. 12 are sectional schematic illustrations showing respective steps of an OLED display TFT manufacturing method in accordance with an embodiment of the present invention;

[0013] FIG. 13 shows a poly-silicon grain structure formed by an FE-RTA crystallization method;

[0014] FIG. 14 shows a poly-silicon grain structure formed by an ELA crystallization method; and

[0015] FIG. 15 is a schematic block diagram showing an electronic device including the OLED display in accordance with an embodiment of the present invention.

DETAILED DESCRIPTION OF THE INVENTION

[0016] FIG. 1 is a schematic diagram showing a basic circuit structure of an AMOLED display 110. The OLED display 110 includes a control circuit 140, a data line driving circuit 160, a scan line driving circuit 180 and a display panel 200. The display panel 200 has a plurality of sub-pixels 210. Each sub-pixel 210 is connected with a data line (D1-Dn) 165 and a scan line (S1-Sn) 187 so as to form a matrix. The sub-pixel 210 receives an image data signal from the data line driving circuit 160 via the data line 165 and receives a switch/address signal from the scan line driving circuit 180 via the scan line 187. The data line driving circuit 160 and the scan line driving circuit 180 are controlled by the control circuit 140.

[0017] The sub-pixel can be designed to contain several TFTs. Generally, each sub-pixel comprises at least a driving TFT for driving a light emitting element and a switch TFT for switching the state of the sub-pixel, as shown in FIG. 2. FIG. 2 schematically shows a basic circuit structure of the sub-pixel 210 in FIG. 1. The sub-pixel 210 has a light emitting element 212 such as an OLED, and a driving TFT 214, which is generally implemented by a PTFT, for driving the light emitting element 212. The sub-pixel 210 further has a switch TFT 216, which is generally implemented by an NTFT, and a capacitor 218. The switch TFT 216 has a gate thereof electrically coupled to the corresponding scan line 187, a drain thereof electrically coupled to the corresponding data line 165, and a source thereof connected with a terminal of the capacitor 218 and a gate of the driving TFT 214. The capacitor 218 has the other terminal thereof connected to a source of the driving TFT 214 and a voltage source Vdd. The driving TFT 214 is connected with the light emitting element 212. The operation of such a circuit is widely known in this field and is not the key point of the present invention, and therefore the description thereof is omitted herein.

[0018] According to the discussion above, the requirement of uniformity for the driving TFT of each sub-pixel in the display panel is very strict so as to avoid luminance mura occurring in the display area. The requirement of electrical performance is very high for the switch TFT for switching the sub-pixel state and the peripheral circuit TFTs. In other words, for an AMOLED display, the requirements for the driving TFT and switch TFT, peripheral circuit TFT are different. The present invention provides a technique so that TFTs meeting different requirements can be manufactured in the same process.

[0019] In an embodiment of the present invention, the N-type TFT and P-type TFT used in the OLED display peripheral circuit, the switch TFT, which is usually implemented by an NTFT and is used in the display area, and the driving TFT, which is usually implemented by a PTFT for driving the light emitting element in the display area are simultaneously manufactured in different regions of the same glass substrate. For the sake of description convenience, the NTFT, PTFT used in the peripheral circuit and the switch TFT used in the display area are generally called "non-driving TFTs". According to the embodiment of the present invention, the non-driving TFT and the driving TFT are manufac-

tured to have different properties which meet the different requirements. The non-driving TFT has excellent electrical performance, while the driving TFT is able to cause the resultant flat display to have good luminance uniformity.

[0020] The process of the AMOLED display TFT manufacturing method of the present invention is shown in FIG. 3 to FIG. 12. In each drawing, the left portion of a first region shows a process for an N-type non-driving TFT, and the right portion shows a process for a P-type non-driving TFT. A second region shows a process for the driving TFT.

[0021] FIG. 3 illustrates the first step of the method in accordance with an embodiment of the present invention. A substrate 10 is provided, the material thereof can be light transparent material such as glass. A buffer layer is formed on the substrate 10. In the present embodiment, the buffer layer comprises a nitride layer 21, of which the material can be silicon nitride, and an oxide layer 23, of which the material can be silicon oxide. An amorphous silicon layer is formed on the buffer layer and then is converted into a first poly-silicon layer 30 by using a first crystallization process. The first crystallization process is a high power laser crystallization process, which is referred to as a standard laser crystallization process. For example, an excimer laser anneal (ELA) method can be used.

[0022] With reference to FIG. 4, the first poly-silicon layer 30 is patterned and subject to n-doping and channel doping. In the NTFT portion, the remaining poly-silicon layer is used as an active area 36, which is further formed to have a drain 36a, a channel 36b and a source 36c. In the PTFT portion, the remaining poly-silicon layer is used as an active area 34. At this time, the active area 34 of the PTFT has not been doped. It is noted that the poly-silicon layer 30 in the second region is entirely removed by any suitable technique such as dry etching. Successively, a first insulating layer 40 is formed over the whole structure. According to various embodiments, the thickness of the first insulating layer 40 is as thin as possible. In practice, the thickness of the first insulation layer 40 is about 200 to 300 angstrom. In the present embodiment, the material of the first insulating layer 40 is oxide such as silicon oxide. According to various embodiments, the material of the first insulating layer 40 can be the same as that of the oxide layer 23 of the buffer layer.

[0023] With reference to FIG. 5, an amorphous silicon layer 50 is formed on the structure of FIG. 4. This amorphous silicon layer 50 is converted into poly-silicon (i.e. a second poly-silicon layer 51 shown in FIG. 6) by using a second crystallization process. According to the present invention, the second crystallization process is different from the first crystallization process. The second crystallization process utilizes a non-laser crystallization technique or a low power laser crystallization technique. The non-laser crystallization technique can be any of solid phase crystallization (SPC), metal induced crystallization (MIC), metal induced lateral crystallization (MILC), field enhanced metal induced lateral crystallization (FE-MILC), field enhanced rapid thermal annealing process, furnace annealing process, rapid thermal process (RTP) and so on. The low power laser crystallization process can be any of lower power excimer laser crystallization, solid state laser crystallization and so on. The respective crystallization processes listed here are only for exemplarity. The invention is not limited hereby.

[0024] With reference to FIG. 7, after patterning, the second poly-silicon layer 51 in the first region is removed, while a portion of the second poly-silicon layer 51 in the second

region is left as an active area **52**. A second insulating layer **45** is formed over the whole structure. The material of the second insulating layer **45** can be oxide as the first insulating layer **40**. However, for further enhancing electrical performance, the insulating layer **45** of the present embodiment is formed to include a lower oxide layer and an upper nitride layer. In practice, it is difficult to distinguish the second insulating layer **45** and the first insulating layer **40** after the second insulating layer **45** is formed.

[0025] As can be seen from the drawing, the thickness of the insulating material from the bottom of the active area **52** to the top of the substrate **10** in the second region (including the nitride layer **21**, oxide layer **23** and first insulating layer **40**) is thicker than that of the insulating material from the bottom of the active areas **34**, **36** to the top of the substrate **10** in the first region (including nitride layer **21** and oxide layer **23** but without the first insulating layer **40**). In contrast, the insulating material between the gate **62** and the active area **52** in the second region includes only the second insulating layer **45**. The insulating material between the gates **64**, **66** and the active areas **34**, **36** in the first region includes the first insulating layer **40** and the second insulation layer **45**. The insulating material between the gates **64**, **66** and the active areas **34**, **36** in the first region is referred to as a first gate insulation layer, and the insulating material between the gate **62** and the active area **52** in the second region is referred to as a second gate insulation layer. The second gate insulation layer is thinner than the first gate insulation layer. The thickness difference between the first and second gate insulation layers is the thickness of the first insulating layer **40**. Taking errors of the respective film thicknesses into consideration) the mentioned thickness difference should be greater than 30 angstrom in general.

[0026] With reference to FIG. 9, portions **34a**, **34c** of the active area in the first region and portions **52a**, **52c** of the active area in the second region are subject to P-doping so as to form drains **34a'**, **52a'** and sources **34c'**, **52c'**.

[0027] With reference to FIG. 10, a first protection layer **70** and a second protection layer **80** are formed over the structure of FIG. 9. In addition, electrodes **92**, **94**, **96** are formed in any suitable manner. The material of the first protection layer **70** can be nitride, and the material of the second protection layer **80** can be oxide.

[0028] With reference to FIG. 11, an intermediate layer **85**, of which the material can be nitride, is formed over the structure of FIG. 10. Then a first planarizing layer **100** is formed over the whole structure so that the surface of the whole structure becomes flat. The material of the first planarizing layer **100** can be transparent material. As shown, a contact hole **101** is formed by any suitable method.

[0029] With reference to FIG. 12, an anode **103** of an OLED is formed on the sidewall of the contact hole **101**. In addition, a second planarizing layer **105** is formed.

[0030] The poly-silicon layer of the active area **52** in the second region is used in the driving TFT for driving the light emitting element, while the poly-silicon layers of the active areas **34**, **36** in the first region are used in the non-driving NTFT and PITFT (e.g. peripheral circuit TFT and switch TFT). The former and latter are induced to crystallize by using different crystallization methods, that is, the first crystallization process and the second crystallization process. The first crystallization process can be the standard laser crystallization method such as ELA. The second crystallization process can be the non-laser crystallization method such as SPC

or the low power (low temperature) laser crystallization method such as low power excimer laser crystallization method. The poly-silicon layers generated by using these two different crystallization processes appear significant difference in grain properties.

[0031] FIG. 13 shows a poly-silicon grain structure formed by an FE-RTA crystallization method, which is a non-laser crystallization method. As can be seen, grains formed by such a method are small and the arrangement thereof is irregular.

[0032] The texture is disordered and has branch-like veins. FIG. 14 shows a poly-silicon grain structure formed by an ELA crystallization method, which is a standard laser crystallization method. As can be seen, grains formed by this method are bigger, and the arrangement thereof is more regular. The texture thereof is ordered as a column texture and has no branch-like veins.

[0033] In general, the grains formed by the standard laser crystallization method and the low power laser crystallization method may be different in size up to 500 angstrom.

[0034] By using the poly-silicon layers made by the standard crystallization method to form the active areas of the peripheral circuit TFTs, excellent electric performance can be obtained. For example, the poly-silicon formed by the standard laser crystallization method has high carrier mobility such as $100 \text{ cm}^2/\text{V}\cdot\text{s}$ or larger than $100 \text{ cm}^2/\text{V}\cdot\text{s}$. However, variation of carrier mobility for such poly-silicon is greater. That is, standard deviation of carrier mobility for such poly-silicon is high. The poly-silicon used in the driving TFT, for which the requirement of electric performance is not so critical, is formed by the non-laser crystallization method or low power laser crystallization method rather than the standard laser crystallization method so that the strip mura can be avoided after the display using the driving TFT is fabricated. The poly-silicon formed by the non-laser crystallization method or low power laser crystallization method has a lower carrier mobility, which is about $10\text{-}40 \text{ cm}^2/\text{V}\cdot\text{s}$. Accordingly, such poly-silicon is not suitable for being used to manufacture the peripheral circuit TFT and switch TFT. However, such carrier mobility is sufficient for the driving TFT for driving the OLED. The driving TFT using the latter poly-silicon has a low carrier mobility standard deviation, that is, the variation is less, the stability is higher. Therefore, the strip mura can be effectively reduced after the display using the driving TFT is fabricated.

[0035] FIG. 15 is a schematic block diagram showing an electronic device **600** including the OLED display **110** in accordance with an embodiment of the present invention. The OLED display **110**, which has the driving TFT, switch TFT and peripheral circuit TFT as shown in FIG. 12, can be a part of the electronic device **600**. The electronic device **600** comprises the OLED display **110** and a power supply **700**. The power supply **700** is coupled to the OLED display **110** to power the OLED display **110**, so that the OLED display can generate images. The electronic device **600** can be a mobile phone, digital camera, PDA, notebook, desk-top computer, television set, satellite navigation device, vehicle display or portable DVD player.

[0036] While the preferred embodiments of the present invention have been illustrated and described in detail, various modifications and alterations can be made by persons skilled in this art. The embodiment of the present invention is therefore described in an illustrative but not restrictive sense. It is intended that the present invention should not be limited to the particular forms as illustrated, and that all modifications

and alterations which maintain the spirit and realm of the present invention are within the scope as defined in the appended claims.

What is claimed is:

1. A method for manufacturing thin film transistors (TFTs) of an organic light emitting diode (OLED) display, said display comprising a peripheral circuit and a plurality of sub-pixels, each sub-pixel having an light emitting element, said method comprising steps of:

- providing a substrate, said substrate having a first region and a second region;
- forming a buffer layer on said substrate;
- forming a first poly-silicon layer on said buffer layer by a first crystallization process;
- patterning said first poly-silicon layer to form active areas of first TFTs in the first region;
- forming a first insulating layer;
- forming a second poly-silicon layer on said first insulating layer by a second crystallization process, which is different from said first crystallization process;
- patterning said second poly-silicon layer to form an active area of a second TFT in the second region;
- forming a second insulating layer; and
- forming gates of said first and second TFTs on said second insulating layer.

2. The method of claim 1, wherein the first TFTs comprise peripheral circuit TFTs used in the peripheral circuit and a switch TFT for switching a state of the sub-pixel, the second TFT comprises a driving TFT for driving the light emitting element.

3. The method of claim 1, wherein the first crystallization process is a standard laser crystallization method.

4. The method of claim 3, wherein the first crystallization process is an excimer laser anneal (ELA) method.

5. The method of claim 1, wherein the second crystallization process is a non-laser crystallization method.

6. The method of claim 1, wherein the second crystallization process is a low power laser crystallization method.

7. The method of claim 1, wherein said first and second crystallization processes are utilized so that said first poly-silicon layer and second poly-silicon layer respectively formed by said first and second crystallization processes have different grain structures.

8. The method of claim 7, wherein said formed first poly-silicon layer has a column texture in which a grain arrangement thereof is more regular, while said formed second poly-silicon layer has a texture in which a grain arrangement thereof is irregular and has branch-like veins.

9. The method of claim 1, wherein said first and second crystallization processes are utilized so that said first poly-silicon layer and second poly-silicon layer respectively formed by said first and second crystallization processes have different grain sizes.

10. The method of claim 9, wherein said first and second crystallization processes are utilized so that said first poly-silicon layer and second poly-silicon layer respectively formed by said first and second crystallization processes have grain sizes differing from each other by a difference no less than 500 angstrom on the average.

11. The method of claim 2, wherein said first and second crystallization processes are utilized so that a carrier mobility standard deviation of said peripheral circuit TFT is greater than that of said driving TFT.

12. An organic light emitting diode (OLED) display, having a peripheral circuit and a display area, said display area including a plurality of sub-pixels, each sub-pixel having a light emitting element, said OLED display comprising:

- a substrate having a first region and a second region;
- first thin film transistors (TFTs) formed on said first region of said substrate, each first TFT comprising a first buffer layer formed on said substrate, an active area formed by a first poly-silicon layer provided on said first buffer layer, a first gate insulation layer covering said active region and a first gate provided on said first gate insulation layer; and
- a second TFT formed on said second region of said substrate, said second TFT comprising a second buffer layer formed on said substrate, an active area formed by a second poly-silicon layer provided on said second buffer layer, a second gate insulation layer covering said active area and a second gate provided on said second gate insulation layer,

wherein said first poly-silicon layer and said second poly-silicon layer have different grain properties, and said first gate insulation layer and said second gate insulation layer have different thicknesses.

13. The OLED display of claim 12, wherein said first TFTs comprise peripheral circuit TFTs used in said peripheral circuit and a switch TFT for switching a state of said sub-pixel, while said second TFT comprises a driving TFT for driving said light emitting element.

14. The OLED display of claim 13, wherein said first poly-silicon layer and said second poly-silicon layer have different grain structures.

15. The OLED display of claim 14, wherein said first poly-silicon layer has a column texture in which a grain arrangement thereof is more regular, while said second poly-silicon layer has a texture in which a grain arrangement thereof is irregular and has branch-like veins.

16. The OLED display of claim 15, wherein said first poly-silicon layer and said second poly-silicon layer have different grain sizes.

17. The OLED display of claim 16, wherein said first poly-silicon layer and second poly-silicon layer have grain sizes differing from each other by a difference no less than 500 angstrom on the average.

18. The OLED display of claim 13, wherein a carrier mobility standard deviation of said peripheral circuit TFT is greater than that of said driving TFT.

19. The OLED display of claim 12, wherein a thickness difference between said first gate insulation layer and said second gate insulation layer is greater than 30 angstrom.

20. The OLED display of claim 12, wherein said OLED display is a part of an electric device, and said electronic device comprises a power supply coupled with said OLED display for powering said OLED display, and wherein said electronic device is a mobile phone, digital camera, PDA, notebook, desk-top computer, television set, satellite navigation device, vehicle display or portable DVD player.

* * * * *

专利名称(译)	制造薄膜晶体管 (TFT) 的方法和具有由其制造的灯的OLED显示器		
公开(公告)号	US20090146927A1	公开(公告)日	2009-06-11
申请号	US12/277041	申请日	2008-11-24
[标]申请(专利权)人(译)	统宝光电股份有限公司		
申请(专利权)人(译)	TPO DISPLAYS CORP.		
当前申请(专利权)人(译)	群创光电		
[标]发明人	WAN TE CHANG LIU YU CHUNG LEE TE YU		
发明人	WAN, TE-CHANG LIU, YU-CHUNG LEE, TE-YU		
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其他公开文献	US8227808		
外部链接	Espacenet USPTO		

摘要(译)

公开了一种有机发光二极管 (OLED) 显示器及其薄膜晶体管 (TFT) 制造方法。根据本发明，用于形成非驱动TFT (例如外围电路TFT和开关TFT) 的有源区的多晶硅层和用于OLED显示器的驱动TFT分别通过使用标准激光结晶方法和非激光结晶来制造。方法或低能激光结晶方法。因此，外围电路TFT具有优异的电性能，例如高载流子迁移率，而OLED驱动TFT具有良好的稳定性，使得所得显示器可以以改善的亮度均匀性操作。

